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Contents

vii *Conference Committee*

NUMERICAL METHODS AND MAXWELL SOLVERS

13568 02 **Comparison of the approximate Beckmann-Kirchhoff and a rigorous scattering model for coherence scanning interferometry modelling (Invited Paper)** [13568-1]

13568 03 **Neural-PDE modeling of reaction-diffusion using time-series imaging for sub-diffraction-limit 3D lithography** [13568-2]

13568 04 **Investigating the optical response of a through silicon via (TSV) for measuring the conic geometry** [13568-3]

13568 05 **Large-scale electromagnetic simulations enabled by the modified Born series with virtual absorbing boundaries** [13568-4]

MACHINE LEARNING IN OPTICAL METROLOGY

13568 07 **Efficient deep-learning ResNet architectures for Mueller-matrix Fourier scatterometry** [13568-6]

13568 08 **Machine learning-driven analysis of thickness variations in multilayer thin film coatings for photonics** [13568-7]

13568 09 **Smart ellipsometry: artificial intelligence for thin film characterization** [13568-8]

13568 0A **Optimizing telescope alignment configuration using finite element methods and machine learning** [13568-9]

SUPERRESOLUTION AND NANOMETROLOGY

13568 0B **Digital twin for 3D confocal microscopy, 3D through focus microscopy and confocal Fourier microscopy (Invited Paper)** [13568-32]

13568 0D **Resolution test of STED microscopy using nanodiamonds with embedded nitrogen-vacancy centers** [13568-12]

13568 0E **Far-field deep sub-wavelength defect sensing using conjugate structured illumination microscopy (c-SIM)** [13568-13]

13568 0F **Sensitivity analysis of multi-defocus features using spatial attention mechanism for optimizing optical measurement in TSOM** [13568-14]

OPTICAL SYSTEMS AND 3D SHAPE METROLOGY

13568 0G **Model-based coherence scanning interferometry for reflectivity and film measurement** [13568-15]

13568 0H **Optical model for 3D reconstruction of aerodynamic surfaces on blades by using pattern projection** [13568-16]

13568 0I **Multi-Gaussian modelling of laser speckle fields from carbon fibre reinforced plastic** [13568-17]

13568 0J **Characterization of slow concave stainless steel surfaces through off-axis LCD null-screens** [13568-18]

13568 0K **Automating structural-thermal-optical performance analysis by linking finite element analysis with optical performance calculations to enable optomechanical parametric study and optimization** [13568-19]

ELLIPSOMETRY, POLARIMETRY, AND OCD

13568 0M **Imaging Mueller matrix ellipsometry for the characterisation of nanoscale structures** [13568-21]

13568 0N **Modeling and validation of a Mueller matrix imaging polarimeter based on liquid crystals and a polarimetric camera** [13568-22]

13568 0O **Comparative characterization of polarization-stable VCSELs: traditional rotating polarizer versus advanced one-shot method** [13568-23]

13568 0P **Combining diffraction efficiency measurements with RCWA for high-precision grating characterization** [13568-24]

INTERFEROMETRY

13568 0R **A matter of perspective: how nanoscale optical defects limit cosmic-scale gravitational wave observations (Invited Paper)** [13568-26]

13568 0S **Model-based reconstruction of reflective freeform surfaces** [13568-27]

13568 0T **Aspheric surface metrology: fringe phase modeling and iterative optimization with radial shearing interferometry** [13568-28]

13568 0U **Fast scanning quantitative phase microscopy with an infinite field of view** [13568-29]

13568 0V **Holography with second-order correlations** [13568-30]

JOINT SESSION: QUANTITATIVE MICROSCOPY

13568 0Y **Comparison of two fit algorithms to find the maximum of a simulated confocal intensity curve** [13568-33]

POSTER SESSION

13568 12 **New characterization method for measuring extinction ratio and retardance with high accuracy of linear polarizers** [13568-38]

13568 13 **Measure a freeform surface using an SLM combined with a commercial Fizeau interferometer** [13568-39]

13568 14 **Evaluation of the anterior corneal surface considered as a free-form using null-screens** [13568-40]

13568 15 **Some aspects for analytically designing flat aspheric converging Fresnel-type imaging mirror** [13568-41]

13568 18 **Design of a freeform lens for the transformation of Gaussian beams into top-hat distributions** [13568-44]

13568 19 **Bandwidth-limited filtering via hybrid Mach-Zehnder interferometer and ring resonator structures** [13568-45]